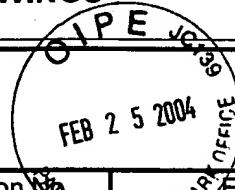


Image  
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# TRANSMITTAL OF FORMAL DRAWINGS

In Re Application Of: **Jack O. Chu, et al.**

Docket No.  
**Y0R920010308US1 (16315)**



Serial No.	Filing Date	Confirmation No.	Examiner	Art Unit
09/838,892	4/20/2001	1665	S. Mulpuri	2812

Invention: **EPITAXIAL AND POLYCRYSTALLINE GROWTH OF Si<sub>1-x-y</sub>Ge<sub>x</sub>C<sub>y</sub> AND Si<sub>1-y</sub>C<sub>y</sub> ALLOY LAYERS ON Si BY UHV-CVD**

Address to:  
**Commissioner for Patents**  
P.O. Box 1450  
Alexandria, VA 22313-1450

Transmitted herewith are:

**11** sheets of formal drawing(s) for this application.

Each sheet of drawing indicates the identifying indicia suggested in 37 CFR Section 1.84(c).

*Signature*

**Steven Fischman**  
Registration No. 34,594  
**SCULLY, SCOTT, MURPHY & PRESSER**  
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(516) 742-4343

Dated: **February 6, 2004**

I certify that this document and attached formal drawings are being deposited on **February 6, 2004** with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

*Signature of Person Mailing Correspondence*

*Typed or Printed Name of Person Mailing Correspondence*